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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
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10/665,693

09/17/2003

Ravinder Aggarwal

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05/03/2006

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EXAMINER

ADAMS, GREGORY W

ART UNIT

PAPER NUMBER

3652

DATE MAILED: 05/03/2006

Please find below and/or attached an Office communication concerning this application or proceeding.

Office Action Summary	Application No. 10/665,693	Applicant(s) AGGARWAL ET AL.	
	Examiner Gregory W. Adams	Art Unit 3652	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 23 March 2006.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-23 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) ☐ Claim(s) _____ is/are allowed.
- 6) ☒ Claim(s) 1-23 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☐ The drawing(s) filed on _____ is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All b) ☐ Some * c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
2. ☐ Certified copies of the priority documents have been received in Application No. _____.
3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|---|---|
| 1) <input checked="" type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413) |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | Paper No(s)/Mail Date. _____ |
| 3) <input type="checkbox"/> Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) | 5) <input type="checkbox"/> Notice of Informal Patent Application (PTO-152) |
| Paper No(s)/Mail Date _____ | 6) <input type="checkbox"/> Other: _____ |

DETAILED ACTION

Continued Examination

A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on March 23, 2006 has been entered.

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

Claims 1-23 is/are rejected under 35 U.S.C. 102(b) as being anticipated by Yonemitsu et al. (US 6,143,083).

With respect to claims 1, 10 & 14-15, Yonemitsu et al. disclose a first substrate handling chamber 100, 500, front docking port 700, robot arm 66, 20, loadlock chamber 30, and a buffer station rack 5. Yonemitsu et al. further discloses different relative pitches between a front opening unified pod and a buffer station rack. C12/L22-28; C6/L63-C7/L65.

With respect to claim 2, Yonemitsu et al. disclose a tool further comprising a buffer station rack B1-4 that holds 300mm wafers.

With respect to claim 3, Yonemitsu et al. disclose a tool further comprising a rear substrate handling chamber where a loadlock chamber is between a first substrate handling chamber and a rear substrate handling chamber.

With respect to claim 4, Yonemitsu et al. disclose a tool wherein a buffer station B1-4 has an inert environment. It is noted that this may be an open cassette or a closed cassette.

With respect to claim 5, Yonemitsu et al. disclose a buffer station B1-4 is purged.

With respect to claim 6, Yonemitsu et al. disclose a buffer station B1-4 is configured as an isolated environment.

With respect to claim 7, Yonemitsu et al. disclose discloses a buffer station B1-4 with an internal volume.

With respect to claim 8, Yonemitsu et al. disclose a buffer station rack B1-4 holds twenty-five 300mm wafers.

With respect to claim 9, Yonemitsu et al. disclose a loadlock chamber 16 has internal volume less than or equal to 9.156 liters.

With respect to claim 11, Yonemitsu et al. disclose a robot arm configured to employ a variable pitch end.

With respect to claim 12, Yonemitsu et al. disclose a substrate handling chamber has atmosphere.

With respect to claim 13, Yonemitsu et al. disclose a substrate handling chamber has reduced pressure.

With respect to claim 16, Yonemitsu et al. disclose a rear substrate handling chamber 100.

With respect to claim 17, Yonemitsu et al. disclose a loadlock chamber substrate capacity of 1 to 7 substrates.

With respect to claim 18, Yonemitsu et al. disclose a load lock chamber rack for holding 300mm wafers.

With respect to claim 19, Yonemitsu et al. disclose a substrate handling chamber at standard atmosphere pressure. Col. 7, Ins. 21-22.

With respect to claim 20, Yonemitsu et al. discloses a substrate handling chamber at reduced pressure.

With respect to claim 21, Yonemitsu et al. disclose a buffer station rack with reduced relative spacing between rack slots. C12/L22-28; C6/L63-C7/L65.

With respect to claim 22, Yonemitsu et al. disclose a buffer station rack at reduced pitch rack, accessed by robot arm. C12/L22-28; C6/L63-C7/L65.

With respect to claim 23, Yonemitsu et al. disclose a robot arm end effectors for transferring substrates. FIGS. 7-8B.

Response to Arguments

Applicant's arguments with respect to claims 1-23 have been considered but are moot in view of the new ground(s) of rejection.

Conclusion

Art Unit: 3652

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Gregory W. Adams whose telephone number is (571) 272-8101. The examiner can normally be reached on M-Th., 8:00-5.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Eileen Lillis can be reached on (571) 272-6928. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

GWA



EILEEN D. LILLIS
SUPERVISORY PATENT EXAMINER
TECHNOLOGY CENTER 3600